

Notice of References Cited

Application/Control No.

09/847,511

Applicant(s)/Patent Under
Reexamination
WANG ET AL.

Examiner

Michael Kornakov

Art Unit

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U.S. PATENT DOCUMENTS

| * | | Document Number Country Code-Number-Kind Code | Date MM-YYYY | Name | Classification |
|---|---|--|-----------------|--------------------|----------------|
| | A | US-4,417,945 | 11-1983 | Komatsuzaki, Yasuo | 438/747 |
| | B | US-5,593,505 | 01-1997 | Erk et al. | 134/1.3 |
| | C | US-5,992,431 | 11-1999 | Weber et al. | 134/135 |
| | D | US-5,988,186 | 11-1999 | Ward et al. | 134/1.3 |
| | E | US-5,003,999 | 04-1991 | Cardani et al. | 134/105 |
| | F | US-4,657,631 | 04-1987 | Noguchi, Hiromichi | 216/27 |
| | G | US-5,816,274 | 10-1998 | Bartram et al. | 134/140 |
| | H | US-4,902,350 | 02-1990 | Steck, Ricky B. | 134/1 |
| | I | US-5,839,460 | 11-1998 | Chai et al. | 134/147 |
| | J | US-5,626,159 | 05-1997 | Erk et al. | 134/147 |
| | K | US-6,257,255 | 07-2001 | Oshinowo, John | 134/141 |
| | L | US-6,240,938 | 06-2001 | Oshinowo, John | 134/147 |
| | M | US-5,279,991 | 01-1994 | Minahan et al. | 438/109 |

FOREIGN PATENT DOCUMENTS

| * | | Document Number Country Code-Number-Kind Code | Date MM-YYYY | Country | Name | Classification |
|---|---|--|-----------------|---------|------|----------------|
| | N | | | | | |
| | O | | | | | |
| | P | | | | | |
| | Q | | | | | |
| | R | | | | | |
| | S | | | | | |
| | T | | | | | |

NON-PATENT DOCUMENTS

| * | | Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages) |
|---|---|--|
| | U | Handbook of Semiconductor Wafer Cleaning Technology edited by W.Kern. Noyes Publications, 1993, page 24. |
| | V | |
| | W | |
| | X | |

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.